

Production Metrology for Precision Surfaces

(Fertigungsmesstechnik für Präzisionsoberflächen)

in the PTB, Braunschweig

Monday, November 8th 2004	
08:30	Welcome and Introduction
	<i>Form Metrology</i>
08:35	1. High Precision Interferometry Chris Evans (Zygo Corporation, Middlefield, CT, USA)
09:35	2. High Resolution Interferometric Metrology in Lithography Bernd Dörband (Carl Zeiss SMT AG)
10:35	Coffee break
11:00	3. The Nano Optic Measuring Machine - NOM - High Accuracy with Deflectometry for Surface Measuring and Figuring Frank Siewert and Heiner Lammert (Berliner Elektronenspeicherringgesellschaft für Synchrotronstrahlung mbH (Bessy), Berlin)
12:00	4. Multiple Sensor Systems for High Accuracy Form Measurement of Flats and Aspheres Michael Schulz, Clemens Elster, Ralf Geckeler, Jens Illema, Ingolf Weingärtner (PTB)
13:00	Lunch
14:00	5. Interferometric Measurement of Cylindrical Surfaces and Lenses with the help of Diffractive Optical Elements Norbert Lindlein and Johannes Schwider (Chair of Optics at the Institute of Optics, Information and Photonics (Max Planck Research Group) at the University of Erlangen-Nürnberg)
15:00	6. Flexible Tools to Support Stitching Interferometry Greg Forbes and Don Golini (QED Technologies, Rochester, NY, USA)
16:00	Coffee break
16:30	7. Surface Figure Metrology of x-ray mirrors using optical interferometry Kazuto Yamauchi (Osaka University, Prec. Eng. Lab.)
17:30	8. Asphere Testing with Computer Generated Holograms Roland Schreiner, Hans Lauth (Jenoptik Laser.Optik.Systeme GmbH)
18:30	End of first day
20:00	Dinner in the Stadthotel, Magnitor
Thursday, November 9th 2004	
	<i>Surface Metrology</i>
8:30	9. Scanning probe microscopy at optical surfaces Frank Eisert (Carl Zeiss, Oberkochen)
9:30	10. Nano-scale roughness analysis of functional surfaces Angela Duparré (Fraunhofer IOF, Jena)
10:30	Coffee break
11:00	11. Optical Roughness Metrology Gert Goch (Bremen University)
	<i>Resumé and Discussion</i>
12:00	Resumé and Discussion Günter Wilkening (CC UPOB)
12:30	End